

ABSTRACT OF THE DISCLOSURE

A stage apparatus including a center slider
movable in XY directions and a substrate stage mounted
on the center slider. The center slider and the
5 substrate stage are connected by plural electromagnet
units to generate a moving force in a predetermined
direction to the substrate stage by application of
electric current to exciting coils. A moving force to
be applied to the substrate stage and its direction are
10 determined in correspondence with movement of the
slider, and an electric current is selectively applied
to the exciting coils of said plural electromagnet
units. Upon application of electric current to the
respective exciting coils, the directions of the
15 electric current applied to the respective exciting
coils are selected so as to reduce a leak magnetic
field around a wafer on the substrate stage.